

・ Surface Particle Defect Test
・ Thickness & Composition Test
・ Hall Effect Test
・ ECV Profiler
・ PL Mapper
・ Microscope
・ Electrochemical C-V Profiling
・ Xray Diffraction
・ Device Performance
・ Photoluminescence
・ Vander Pauw-Hall
・ Photoreflectance
・ Resistivity Mapping



PL Mapper: Nanometrics製 RPMBLUE-FS-M
顕微鏡: Olympus製MX51



Surface Defect Test: KLA-Tencor製 Surfscan6220
Sheet Resistance Test: Leighton製 LEI-1510-RP非接触測定システム
Thickness & Composition Test : Jordan Valley製 QC3 High Resolution X-ray Diffractometer



Hall Effect Test: Nanometrics製 HL5500PC
ECV Profiler: Nanometrics製 ECV-PRO-WL